

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :  
Yuji MATSUYAMA, et al. : EXAMINER: JOLLEY, K.  
SERIAL NO: 09/886,213 :  
FILED: June 22, 2001 : GROUP ART UNIT: 1762  
FOR: HEAT TREATMENT : DATE ALLOWED: March 3, 2005  
METHOD, HEAT  
TREATMENT APPARATUS  
AND TREATMENT  
SYSTEM

COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VA 22313-1450

SIR:

The following comment is in response to the Statement of Reasons for Allowance provided in the Notice of Allowability dated March 3, 2005.

The Statement of Reasons For Allowance included on page 2 of the Notice of Allowability states that the prior art does not "teach or fairly suggest a method of heat-treating a coated substrate in a heating chamber while controlling/lowering an oxygen concentration of the heat-treatment atmosphere...." The Applicants submit that this statement does not reflect the claimed subject matter recited in allowed independent Claims 35 and 36 of the present application. Claims 35 and 36 do not recite controlling/lowering an oxygen concentration of the heat-treatment atmosphere, as suggested by the Statement.

Accordingly, it is respectfully submitted that the Statement of Reasons for Allowance does not accurately reflect the subject matter recited in Claims 35 and 36, and thus the Applicants submit that the Statement of Reasons for Allowance is not applicable to Claims 35 and 36.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
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